

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Min-Su Fung, et al.  
Title: NON-CONTACT MOBILE CHARGE MEASUREMENT WITH  
LEAKAGE BAND-BENDING AND DIPOLE CORRECTION  
Docket: 29318US2

INFORMATION DISCLOSURE STATEMENT

Mail Stop Patent Application  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

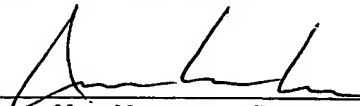
Sir:

In accordance with 37 C.F.R. § 1.98, applicant is submitting herewith Form PTO-1449 listing references for consideration by the Examiner. Pursuant to 37 C.F.R. 1.98(d), copies of the listed references are not enclosed herewith because the references were previously cited to, or cited by, the U.S. Patent Office in earlier patent application serial no. 08/874,644, which application is relied on for an earlier effective filing date under 35 U.S.C. 120.

If any fees are required by this communication, please charge such fees to our Deposit Account No. 16-0820, Order No. 29318US2.

Respectfully submitted,

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By   
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Date: 3/25/04

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. 29318US2	SERIAL NO.
<b>INFORMATION DISCLOSURE CITATION BY APPLICANT</b> <i>(USE SEVERAL SHEETS IF NECESSARY)</i>				APPLICANT: Min-Su Fung, et al.	
				FILING DATE:	GROUP ART UNIT:

U S PATENT DOCUMENTS							
Examiner Initial		Document No.	Date	Name	Class	Subclass	Filing Date If Appropriate
	A	4,236,165	4/1982	Szedon			
	B	4,812,756	3/1989	Curtis, et al.			
	C	5,216,362	6/1993	Verkuil			
	D	5,498,974	3/1996	Verkuil, et al.			
	E	5,767,693	6/1998	Verkuil			
	F	5,834,941	11/1998	Verkuil, et al.			
	G						
	H						

FOREIGN PATENT DOCUMENTS							
		Document No.	Date	Country	Class	Subclass	Translation
	I						
	J						

OTHER REFERENCES <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>	
K	Solid State Technology, Test/Measurement, "Monitoring Electrically Active Contaminants to Assess Oxide Quality", Gregory S. Horner, et al., June 1985, PennWell Publishing Company, 4 Pages.
L	Semiconductor International, "A New Approach for Measuring Oxide Thickness", Tom G. Miller, July 1995, Cahners Publishing Company, 2 Pages.
M	"COS Testing Combines Expanded Charge Monitoring Capabilities with Reduced Costs", Michael A. Peters, Semiconductor Fabtech 95, 4 Pages.
N	Process Monitoring, "Corona Oxide Semiconductor Test", Semiconductor Test Supplement, February/March 1995, Pages S-3 and S-5.
O	"Quantox™ Non-Contact Oxide Monitoring System", John Bickley, 1995 Keithley Instruments, Inc., No. 1744, 6 Pages.

Examiner:	Date Considered
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<b>*Examiner:</b>	Initial if reference considered, regardless of whether citation is in conformance with MPEP 609; Draw line through citation if not in conformance <u>and</u> not considered. Include copy of this form with next communication to applicant.
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